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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

GROUP 1700

NOV 03 2003

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Applicant(s): T. HIROSE, et al

Serial No.: 09/800,495

Filed: March 8, 2001

For: METHOD OF DETECTING AND MEASURING ENDPOINT OF
POLISHING PROCESSING AND ITS APPARATUS AND
METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE
USING THE SAME

Group: 1765

Examiner: L. Umez Eronini

AMENDMENT AFTER FINAL ACTION

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

October 30, 2003

Sir:

In response to the Office Action July 30, 2003, the following amendments and remarks are respectfully submitted in connection with the above-identified application, as listed below and as set forth on the following pages:

Amendment of the Claims; and

Remarks are included following the amendments.

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